

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	40	(tele-centric\$4 or tele adj2 centric\$3 or telecentric\$4)same(ghost\$4)	US-PGPUB; USPAT	OR	ON	2005/05/27 07:53
L2	3906	(tele-centric\$4 or tele adj2 centric\$3 or telecentric\$4)same(imag\$3)	US-PGPUB; USPAT	OR	ON	2005/05/27 07:49
L3	31	2 same(ghost\$4)	US-PGPUB; USPAT	OR	ON	2005/05/27 07:55
L4	135	2 same(planar\$4 or curfac\$4)	US-PGPUB; USPAT	OR	ON	2005/05/27 07:45
L5	1887	2 same(planar\$4 or surfac\$4)	US-PGPUB; USPAT	OR	ON	2005/05/27 07:45
L6	21	5 same(ghost\$4)	US-PGPUB; USPAT	OR	ON	2005/05/27 07:45
L7	5152	(tele-centric\$4 or tele adj2 centric\$3 or telecentric\$4)	US-PGPUB; USPAT	OR	ON	2005/05/27 07:49
L8	25	7 same(ghost\$4 near10 imag\$3)	US-PGPUB; USPAT	OR	ON	2005/05/27 10:50
L9	1	"5748305".PN.	USPAT; USOCR	OR	ON	2005/05/27 07:52
L10	1	"5583632".PN.	USPAT; USOCR	OR	ON	2005/05/27 07:52
L11	1	"5251010".PN.	USPAT; USOCR	OR	ON	2005/05/27 07:52
L12	1	"6563650".PN.	USPAT; USOCR	OR	ON	2005/05/27 07:53
L13	1	"6324014".PN.	USPAT; USOCR	OR	ON	2005/05/27 07:53
L14	1	"6220713".PN.	USPAT; USOCR	OR	ON	2005/05/27 07:53
L15	1	"6220713".PN.	USPAT; USOCR	OR	ON	2005/05/27 07:53
L16	1	"6220713".PN.	USPAT; USOCR	OR	ON	2005/05/27 07:53
L17	1	"6195209".PN.	USPAT; USOCR	OR	ON	2005/05/27 07:54
L18	1	"6185047".PN.	USPAT; USOCR	OR	ON	2005/05/27 07:57
L19	1	"6023365".PN.	USPAT; USOCR	OR	ON	2005/05/27 07:57
L20	1	"5999306".PN.	USPAT; USOCR	OR	ON	2005/05/27 07:57
L21	1	"5999306".PN.	USPAT; USOCR	OR	ON	2005/05/27 07:58

L22	1	"5548443".PN.	USPAT; USOCR	OR	ON	2005/05/27 07:58
L23	1	"6222676".PN.	USPAT; USOCR	OR	ON	2005/05/27 10:50
L24	1	"6147808".PN.	USPAT; USOCR	OR	ON	2005/05/27 10:50
L25	1	"6124977".PN.	USPAT; USOCR	OR	ON	2005/05/27 10:50


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Key: IEEE JNL = IEEE Journal or Magazine, IEEE JNL = IEEE Journal or Magazine, IEEE CNF = IEEE Conference, IEEE CNF = IEEE Conference, IEEE STD = IEEE Standard

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